

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Jones et al.

Serial No.: Not Yet Assigned

Group Art Unit: Unknown

Filing Date: Concurrently Herewith

Examiner: Unknown

For: **METHOD AND APPARATUS FOR DEPOSITION & FORMATION OF METAL SILICIDES**

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT


Sir:

Under the provisions of 37 CFR §1.97 through §1.99 and pursuant to applicants' duty of disclosure under 37 CFR §1.56, applicants respectfully bring the following documents, listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. Copies of the listed documents are provided herewith for the convenience of the Examiner. This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicants are aware.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's Deposit Account No. 09-0458.

Respectfully submitted,



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INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

ATTY DOCKET NO.

FIS920030204

SERIAL NO.

Not Yet Assigned

Jones et al.

FILING

Concurrently Herewith

GROUP

Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	5,047,367	09/10/1991	Wei et al.			
	5,536,676	07/16/1996	Cheng et al.			
	6,184,132	02/06/2001	Cantell et al.			
	6,221,764	04/24/2001	Inoue			
	6,323,130	11/27/2001	Brodsky et al.			
	6,451,693	09/17/2002	Woo et al.			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		"RTP technology for tomorrow", Vol. 41, Issue 6, June 1, 1998, 11 pages, http://216.239.33.100/search?q=cache:rez...P+technology+for+tomorrow&hl=en&ie=UTF-8
		"Low Temperature Polysilicon Technology for Advanced Display Systems", Tolis Voutsas, www.sharp.co.jp/corporate/rd/journala-69/pdf/69-10p, pp. 51-56, Sept. 24, 1997

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.